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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/875,063	06/06/2001	Warren M. Farnworth	4245US (98-0288)	7843
24247	7590	11/14/2005	EXAMINER	
TRASK BRITT			RACHUBA, MAURINA T	
P.O. BOX 2550			ART UNIT	
SALT LAKE CITY, UT 84110			PAPER NUMBER	

3723

DATE MAILED: 11/14/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

Office Action Summary

Application No.

09/875,063

Applicant(s)

FARNWORTH ET AL.

Examiner

M Rachuba

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-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☒ Responsive to communication(s) filed on 22 August 2005.
- 2a) ☐ This action is **FINAL**. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 1-32,34-66 and 68-75 is/are pending in the application.
- 4a) Of the above claim(s) _____ is/are withdrawn from consideration.
- 5) ☐ Claim(s) _____ is/are allowed.
- 6) ☒ Claim(s) 32,34-36,66 and 68-70 is/are rejected.
- 7) ☐ Claim(s) _____ is/are objected to.
- 8) ☐ Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☒ The drawing(s) filed on 05 March 2003 is/are: a) ☒ accepted or b) ☐ objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☐ All b) ☐ Some * c) ☐ None of:
- ☐ Certified copies of the priority documents have been received.
 - ☐ Certified copies of the priority documents have been received in Application No. _____.
 - ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

* See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- | | |
|--|---|
| 1) <input type="checkbox"/> Notice of References Cited (PTO-892) | 4) <input type="checkbox"/> Interview Summary (PTO-413)
Paper No(s)/Mail Date. _____ |
| 2) <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948) | 5) <input type="checkbox"/> Notice of Informal Patent Application (PTO-152) |
| 3) <input checked="" type="checkbox"/> Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)
Paper No(s)/Mail Date <u>9/26/05</u> . | 6) <input type="checkbox"/> Other: _____ |

DETAILED ACTION

Continued Examination Under 37 CFR 1.114

1. A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on 22 August 2005 has been entered.

Election/Restrictions

2. Applicant's election without traverse of group II in Paper No. 5 is acknowledged.
3. Claims 1-31, 37-65 and 71-75 are withdrawn from further consideration pursuant to 37 CFR 1.142(b) as being drawn to a nonelected invention, there being no allowable generic or linking claim. Election was made **without** traverse in Paper No. 5.

Claim Rejections - 35 USC § 102

4. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

5. Claims 32, 34-36, 66, and 68-70 are rejected under 35 U.S.C. 102(b) as being clearly anticipated by Wark et al, 5,809,987. '987, figures 1-6 and their descriptions, discloses a method for singulating a plurality of semiconductor devices locate on a substrate, the method comprising: providing a saw having at least one blade 32 and a

table (inherently holding the chuck); providing a chuck **12** having at least one cutting pedestal **34**, the chuck mounted on the table, the chuck for holding the substrate during cutting thereof by the saw; providing a substrate **20** having a plurality of semiconductor devices located thereon; placing the substrate in the chuck; aligning the substrate in the chuck; supporting at least one semiconductor device on a portion of the chuck such that at least one of the pedestal partially supports a portion of the substrate; applying a vacuum **38** to a portion of the at least one semiconductor device supported on a portion of the at least one cutting pedestal of the chuck, thereby predisposing the portion of the at least one semiconductor device to remain in contact with the at least one cutting pedestal; and sawing at least one semiconductor device from the substrate by laterally indexing of the saw using one of a multiple-of a fixed interval and a variable interval (figure 1, showing the cutting interval). '987 also discloses supporting the plurality of semiconductor devices on a portion of the chuck, and supporting the plurality of semiconductor devices on portions of the chuck during the sawing thereof from the substrate.

6. Regarding claims 34 and 68, it is the examiner's position that in performing the sawing of the semiconductor wafer, the plurality of devices are sawed from the substrate at substantially the same time.

Response to Arguments

7. Applicant's arguments filed 22 August 2005 have been fully considered but they are not persuasive. Applicant argues that '987 is not prior art regarding the inventions of claims 32, 35, 66, 69 and 70 because '987 does not explicitly disclose indexing the

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saw using one of a multiple of a fixed interval and a variable interval. The examiner disagrees. '987, figure 1, discloses the substrate with the devices 22 and streets indices 24, forming a pattern on the wafer that devices the devices. Inherently, either the saw blade or the chuck must be indexed to position the saw blade relative to the row of devices to be cut, resulting in the saw being laterally indexed relative to the substrate, and the interval may be fixed or variable, see column 4, lines 31-50.

Conclusion

8. Any inquiry concerning this communication or earlier communications from the examiner should be directed to M Rachuba whose telephone number is 571-272-4493. The examiner can normally be reached on Monday-Fridays.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Joseph Hail can be reached on 571-272-4485. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

M Rachuba
Primary Examiner
Art Unit 3723

